

Notice of References Cited	Application/Control No. 10/798,822	Applicant(s)/Patent Under Reexamination CYGANSKI ET AL.	
	Examiner Caleen O. Sullivan	Art Unit 1756	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,913,872	07-2005	Sturtevant et al.	430/322
*	B	US-5,391,465	02-1995	Feely, Wayne E.	430/325
*	C	US-2002/0142232	10-2002	Kling et al.	430/5
*	D	US-4,571,377	02-1986	McGinniss et al.	430/281.1
*	E	US-5,532,114	07-1996	Bae, Sang M.	430/312
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	55-153935	12-1980	JP	Toshiaki	
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Wang, L., et al., "Three-Dimensional Microfabrication by Two-Photon-Initiated Polymerization With A Low-Cost Microlaser." Optics Letter, 2002, August, Vol.27, No. 15, 1348-1350.
	V	Boto, A.N. et al., "Quantum Interferometric Optical Lithography: Exploiting Entanglement to Beat the Diffraction Limit." Physical Review Letters, 2000, September, Vol.85, No. 13, 2733-2736.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.